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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
HONGO, T.

Application No.: 09/536,721

Confirmation No. 5386

Filed: March 28, 2000

Group: 1763

Title: MICROWAVE PLASMA PROCESSING APPARATUS FOR
CONTROLLING A TEMPERATURE OF A WAVELENGTH
REDUCING MEMBER

Examiner: CROWELL, A.

* * * *

06/27/2003 HALI11 00000060 09536721

June 26, 2003

01 FC:1202 18.00 DA
02 FC:1201 168.00 DA

AMENDMENT

Hon. Commissioner of Patents
Washington, DC 20231

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7/2/03
mJ

Sir:

Responsive to the Office Action dated April 3, 2003, please amend the above-identified application as follows.

IN THE CLAIMS:

Please amend claim 21 as follows:

21. (Amended) A microwave plasma processing apparatus comprising:
- a wavelength reducing member constructed and arranged to reduce a wavelength of a microwave transmitted therethrough;
 - a slot electrode guiding the microwave exiting the wavelength reducing member, the slot electrode provided adjacent to the wavelength reducing member;
 - a process chamber into which the microwave exiting the slot electrode is introduced so that a plasma is generated by the microwave within the process chamber;
 - a first temperature control device comprising: